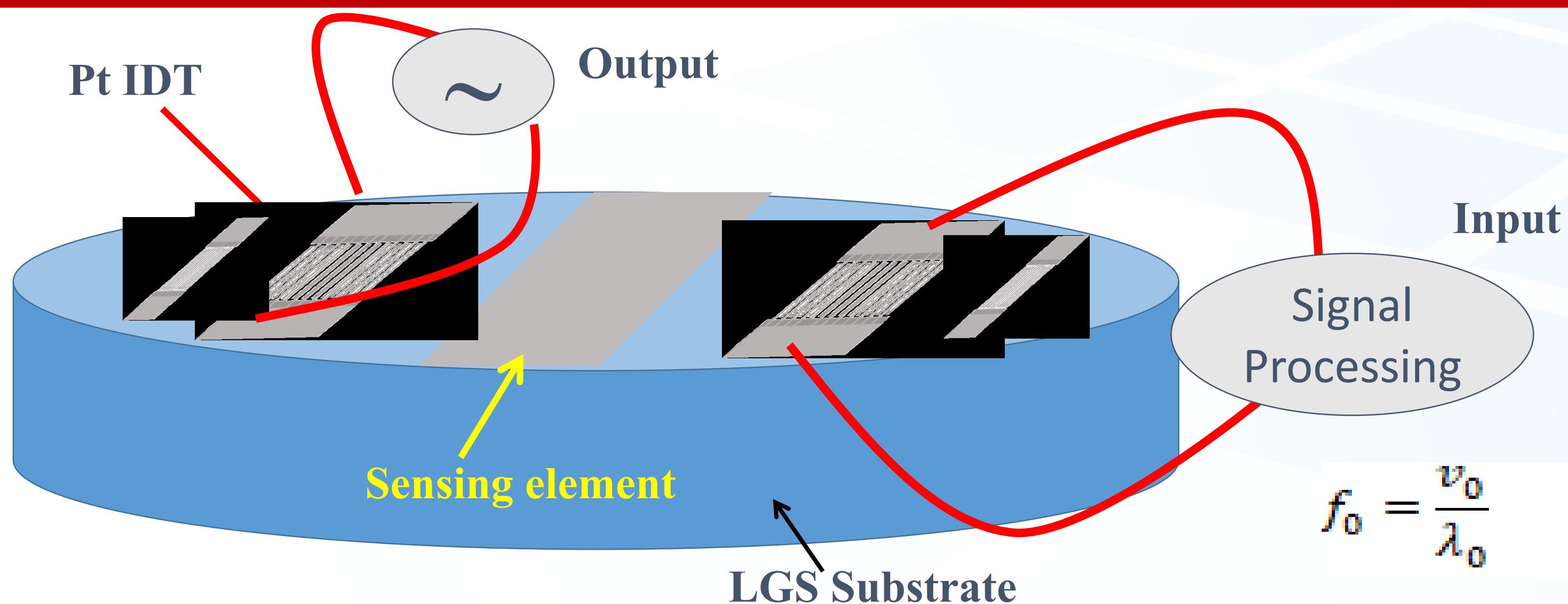


High temperature CO₂ sensing characteristics of Langasite based SAW sensor and Langasite MEMS micro-cantilever gas sensor

Mass loading effect in SAW sensor



$$f_0 = \frac{v_0}{\lambda_0} \quad (1)$$

$$\frac{\Delta v}{v_0} = -\frac{\omega v_0 \rho_s}{4} \left(\frac{v_{x0}^2}{\omega P} + \frac{v_{y0}^2}{\omega P} + \frac{v_{z0}^2}{\omega P} \right) \quad (2)$$

Δv is the change in the SAW velocity, ω is the angular resonant frequency ($=2\pi f_0$),

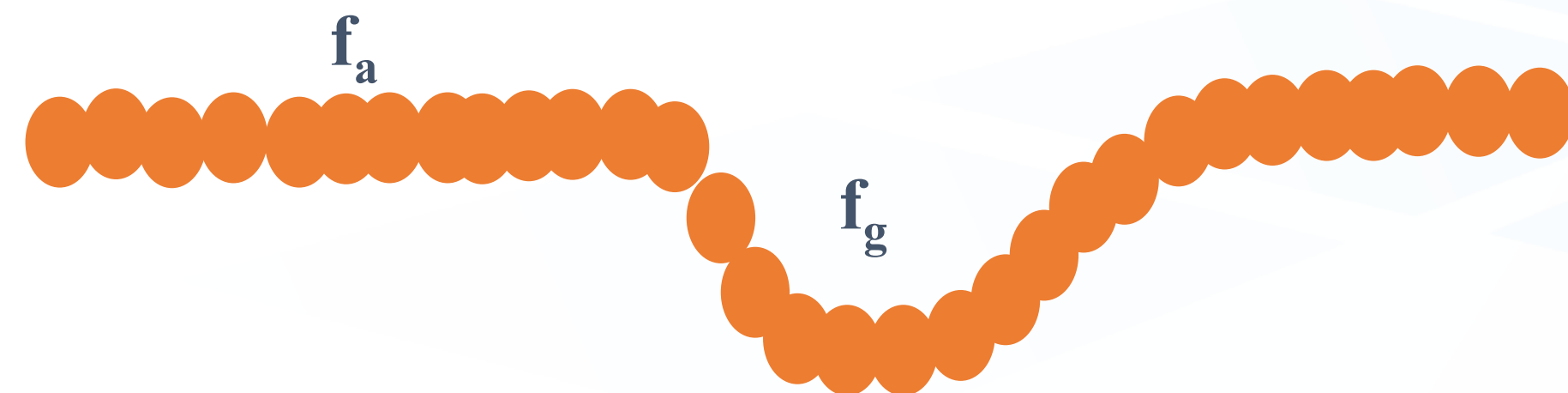
P is the power density

v_{x0} , v_{y0} , v_{z0} are the SAW particle velocity at the surface with respect to different directions, respectively.

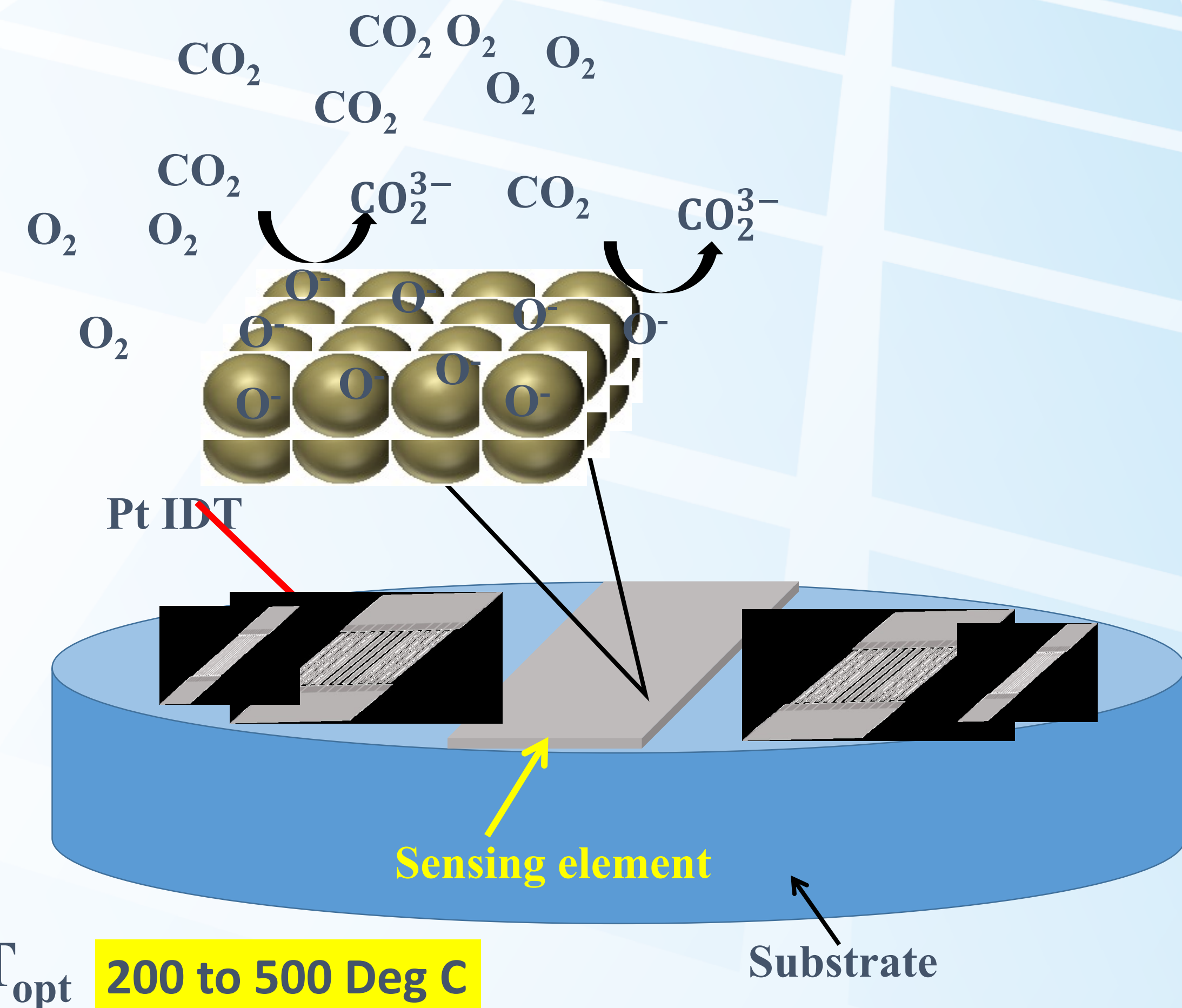
ρ_s is the surface mass density,

$v_{x0}^2/\omega P$ is constant, depends on the materials only

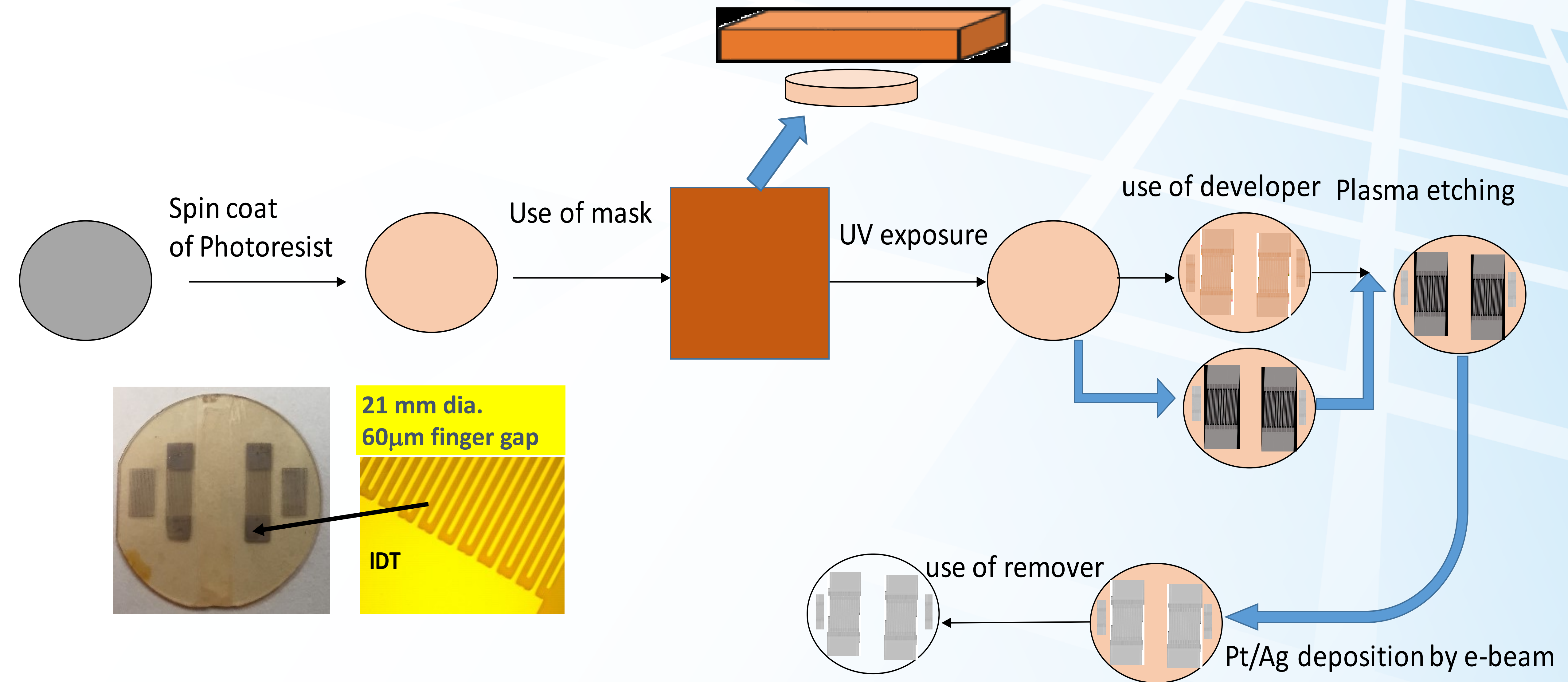
Sensing Mechanism for SAW sensor



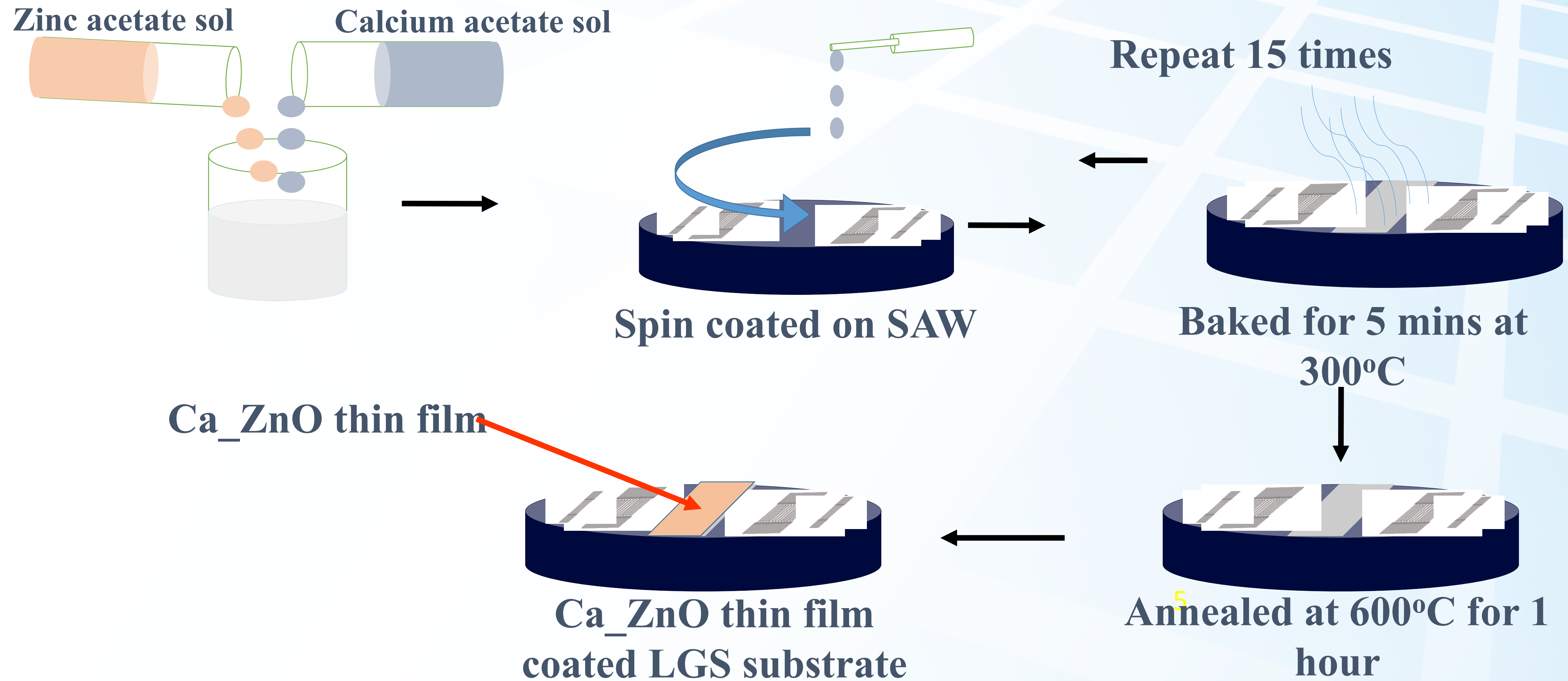
$$\text{Response (S)} = (f_a - f_g) / f_a$$



Fabrication process

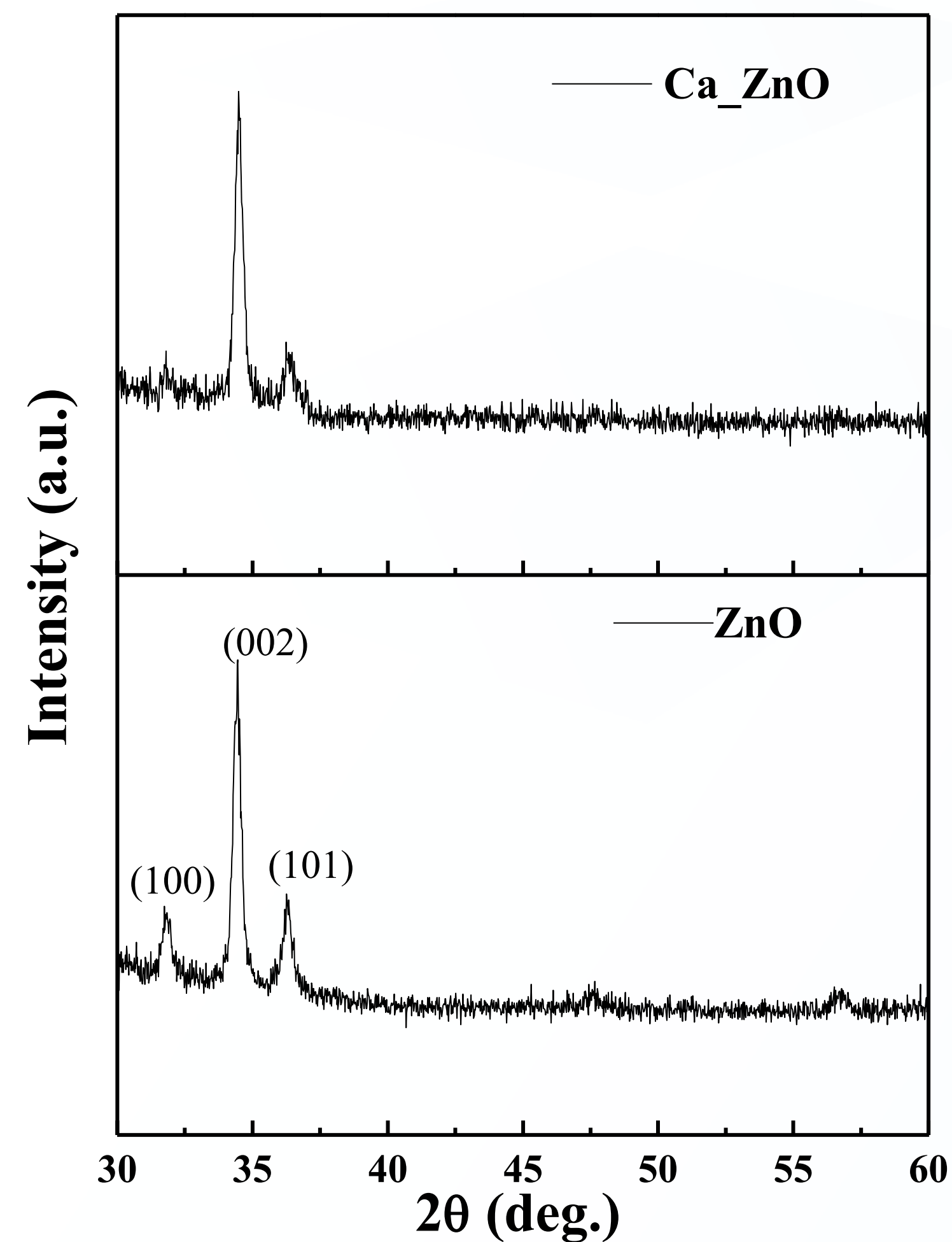


Synthesis of Calcium doped ZnO thin film

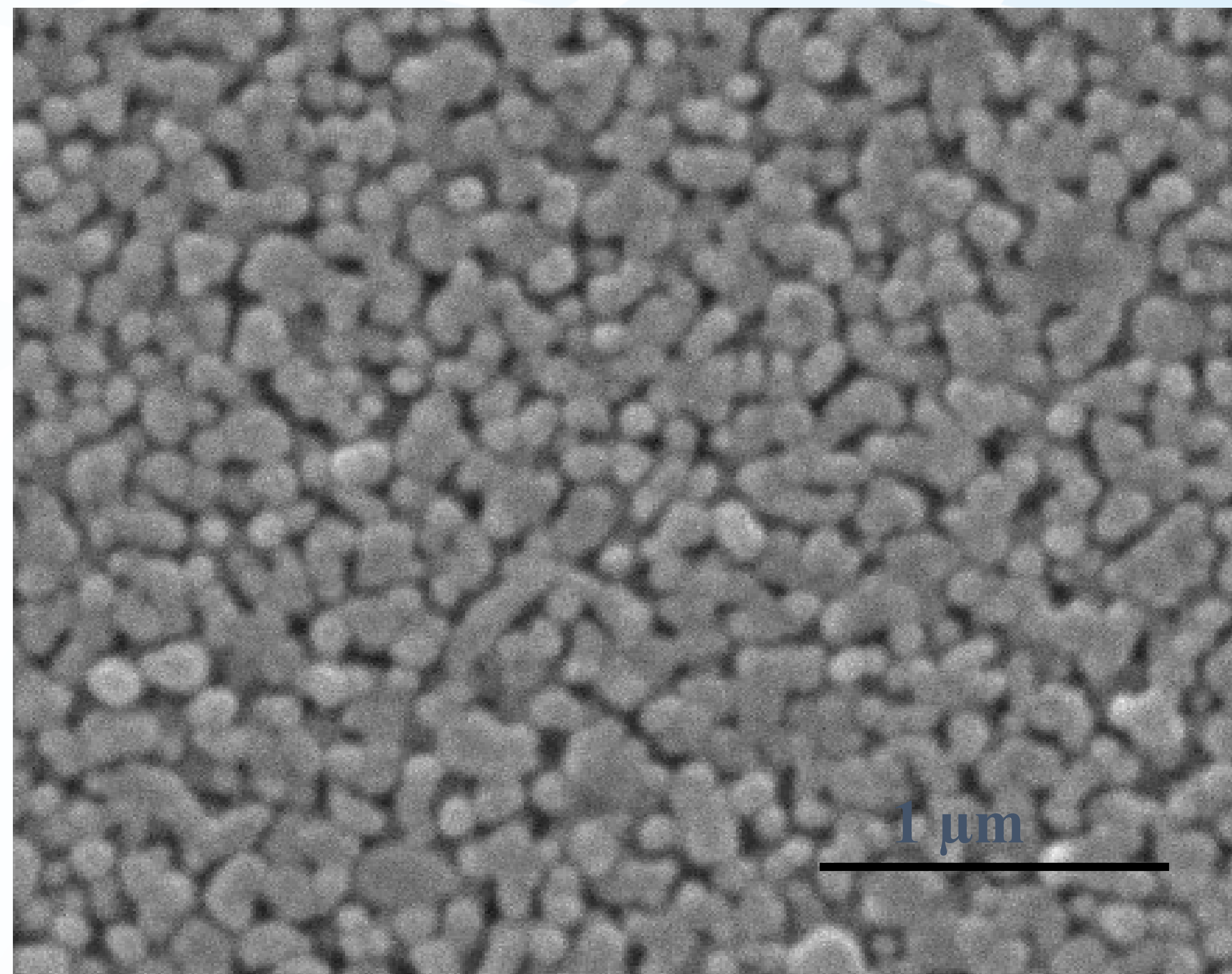


Phase formation and microstructure of Ca_{0.9}ZnO thin film

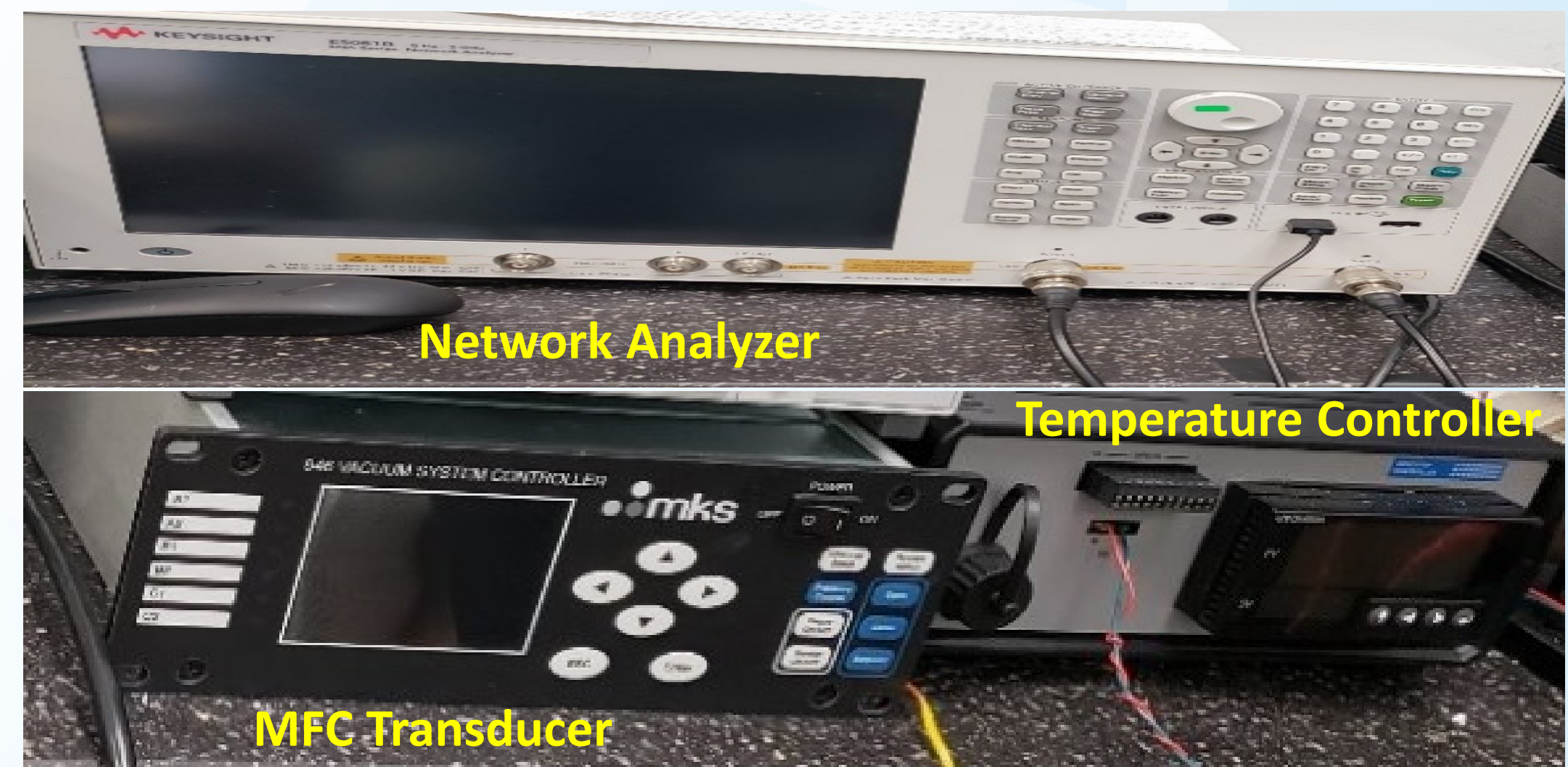
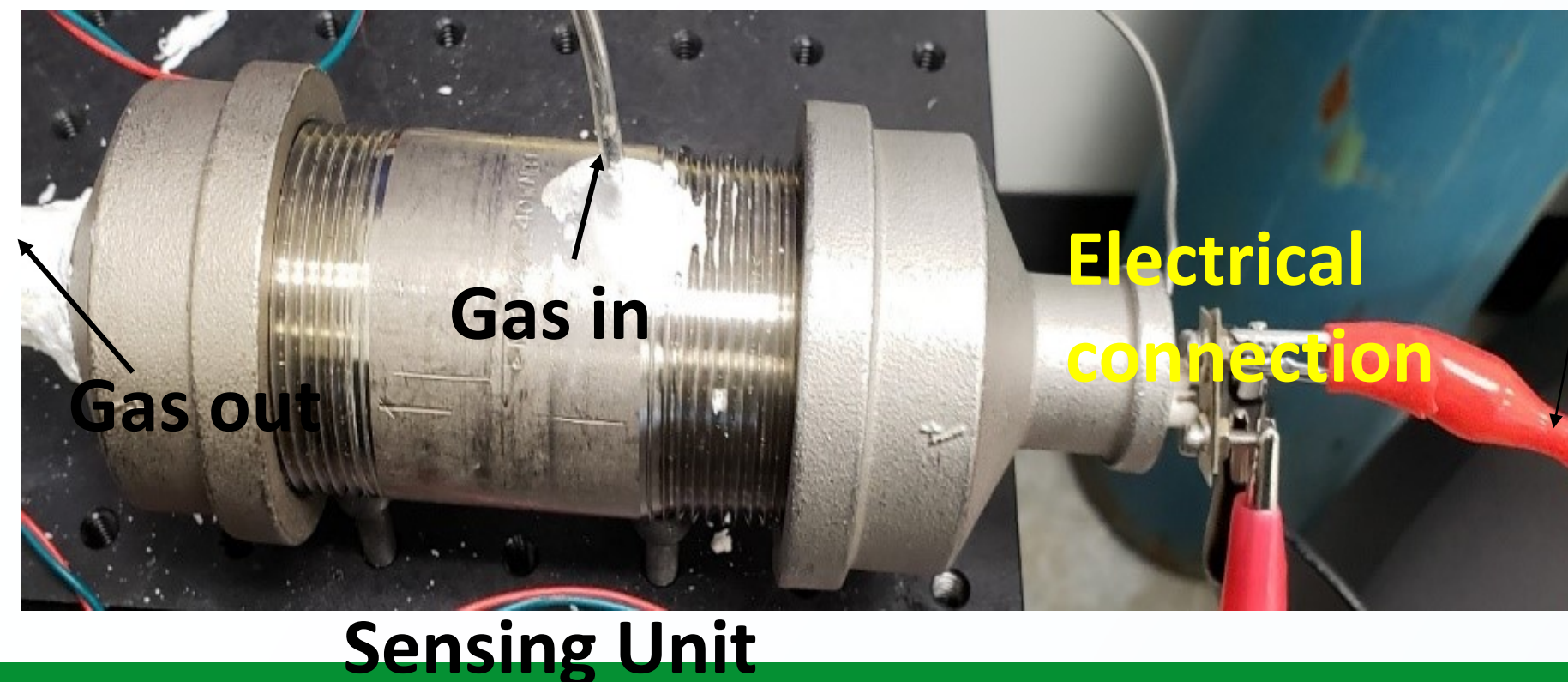
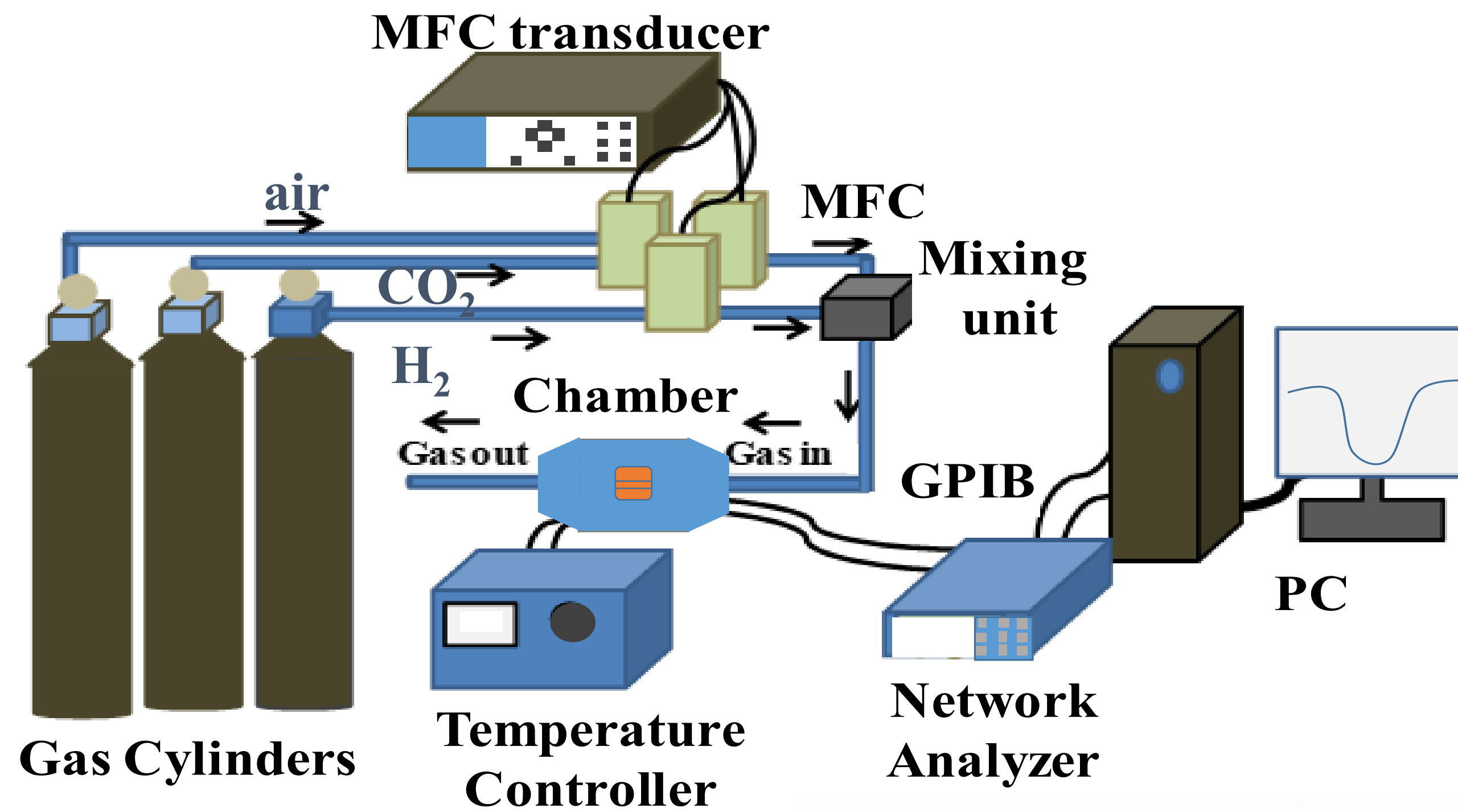
XRD



SEM Microstructure of Ca_{0.9}ZnO thin film

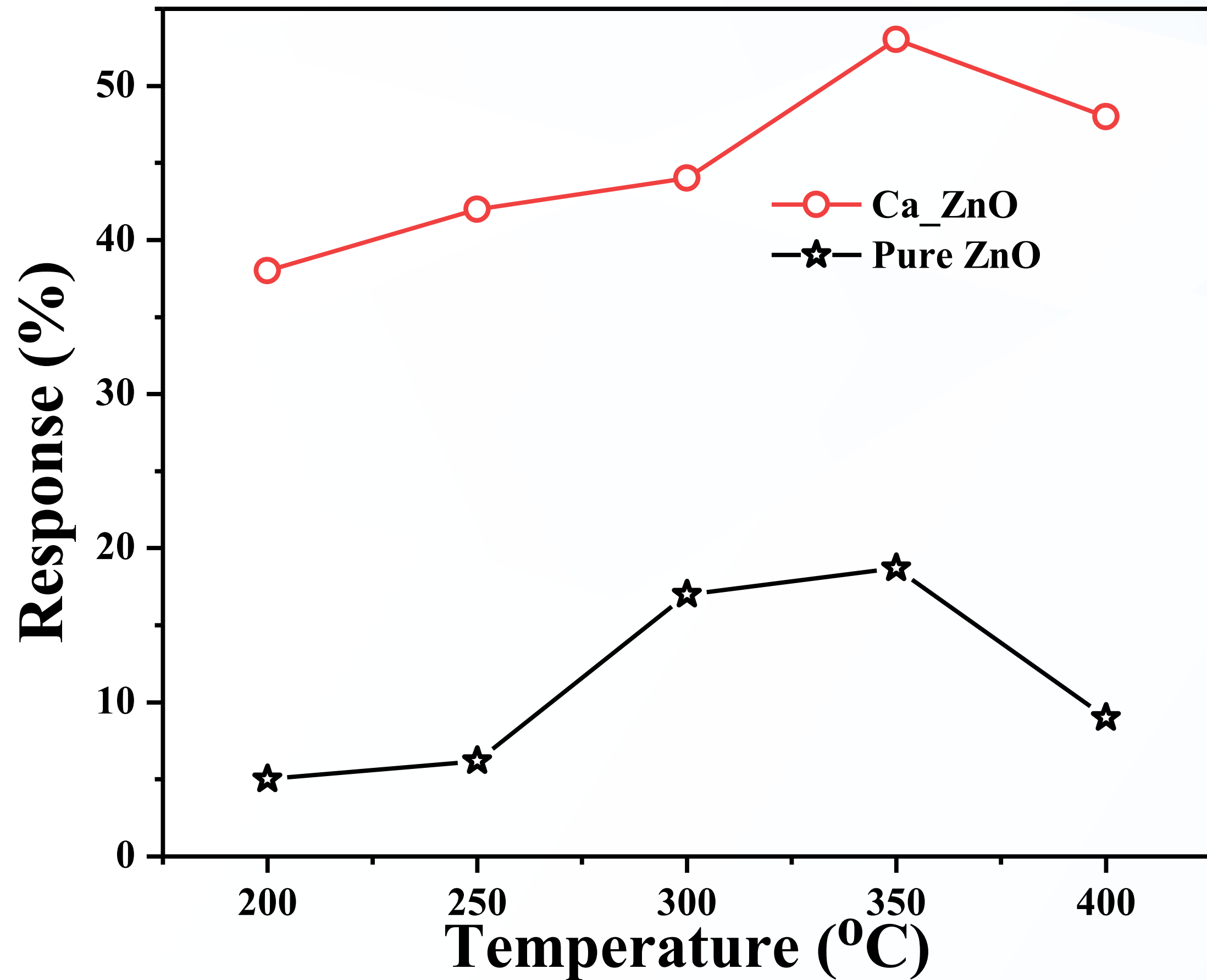


experiment setup

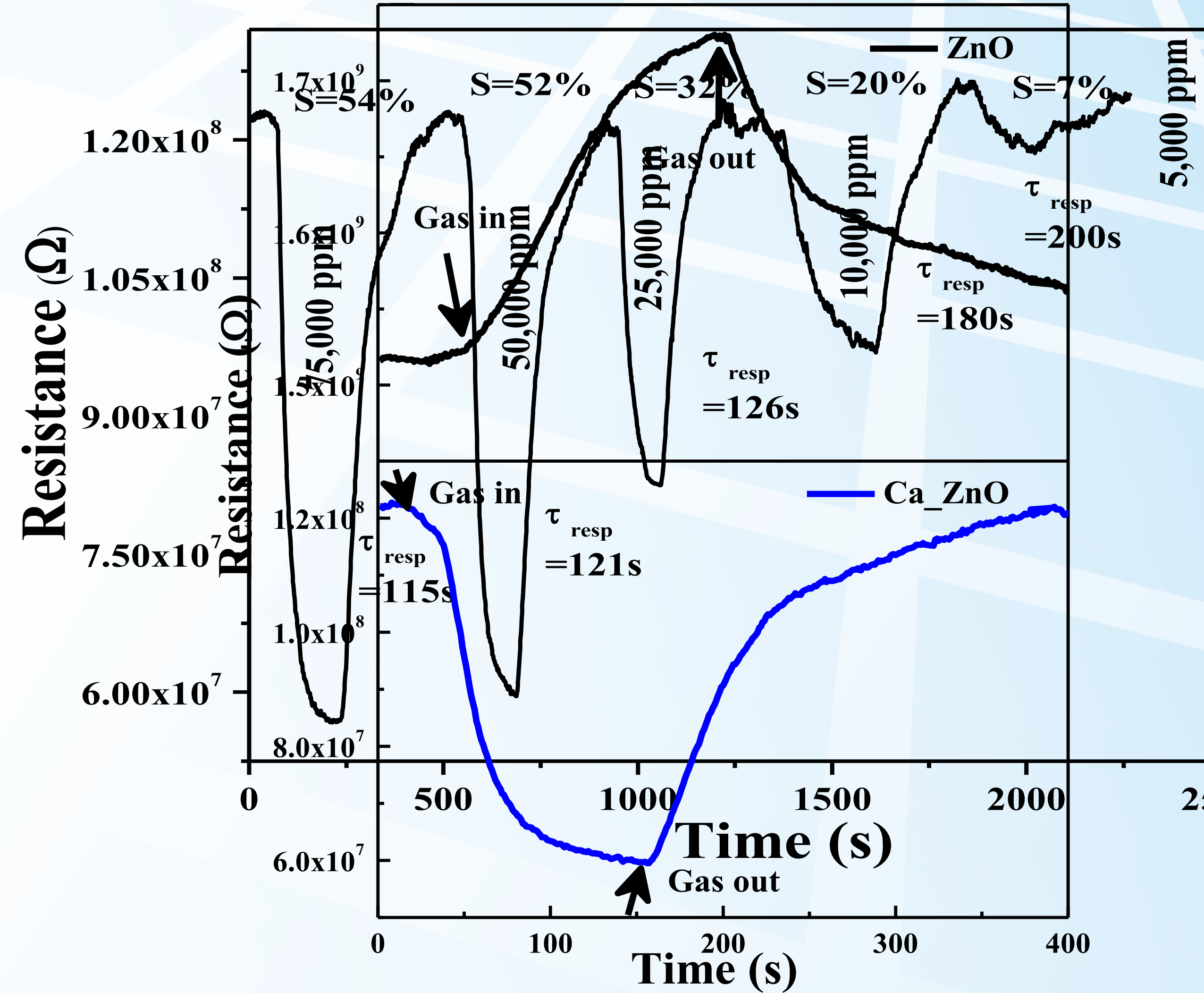


CO₂ sensing of chemo-resistive Ca_ZnO thin film

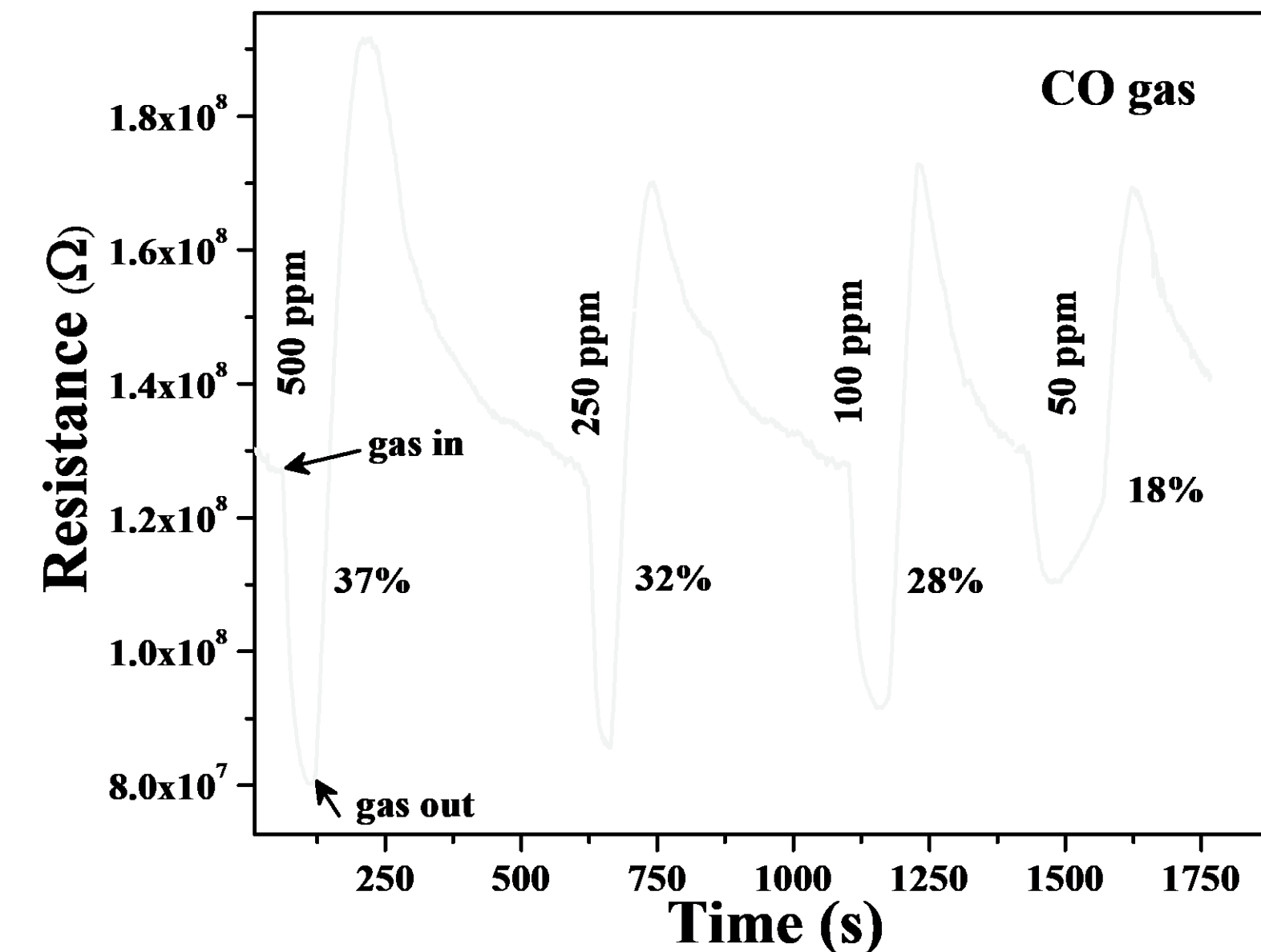
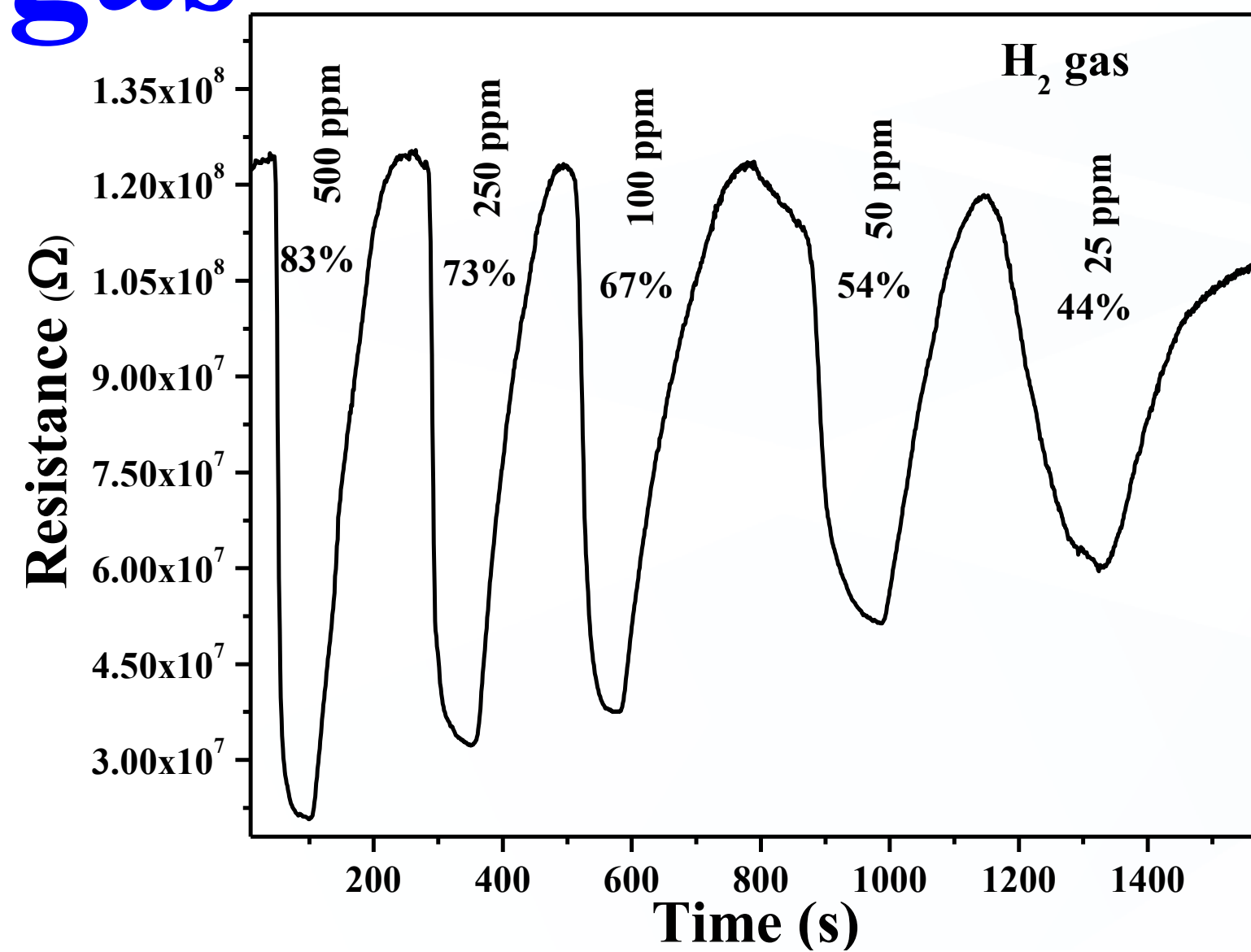
Temperature effect on 50,000 ppm CO₂ response



Concentration dependence of CO₂ response in Ca_ZnO thin film



Cross-sensitivity of CO₂ in H₂ and CO gas

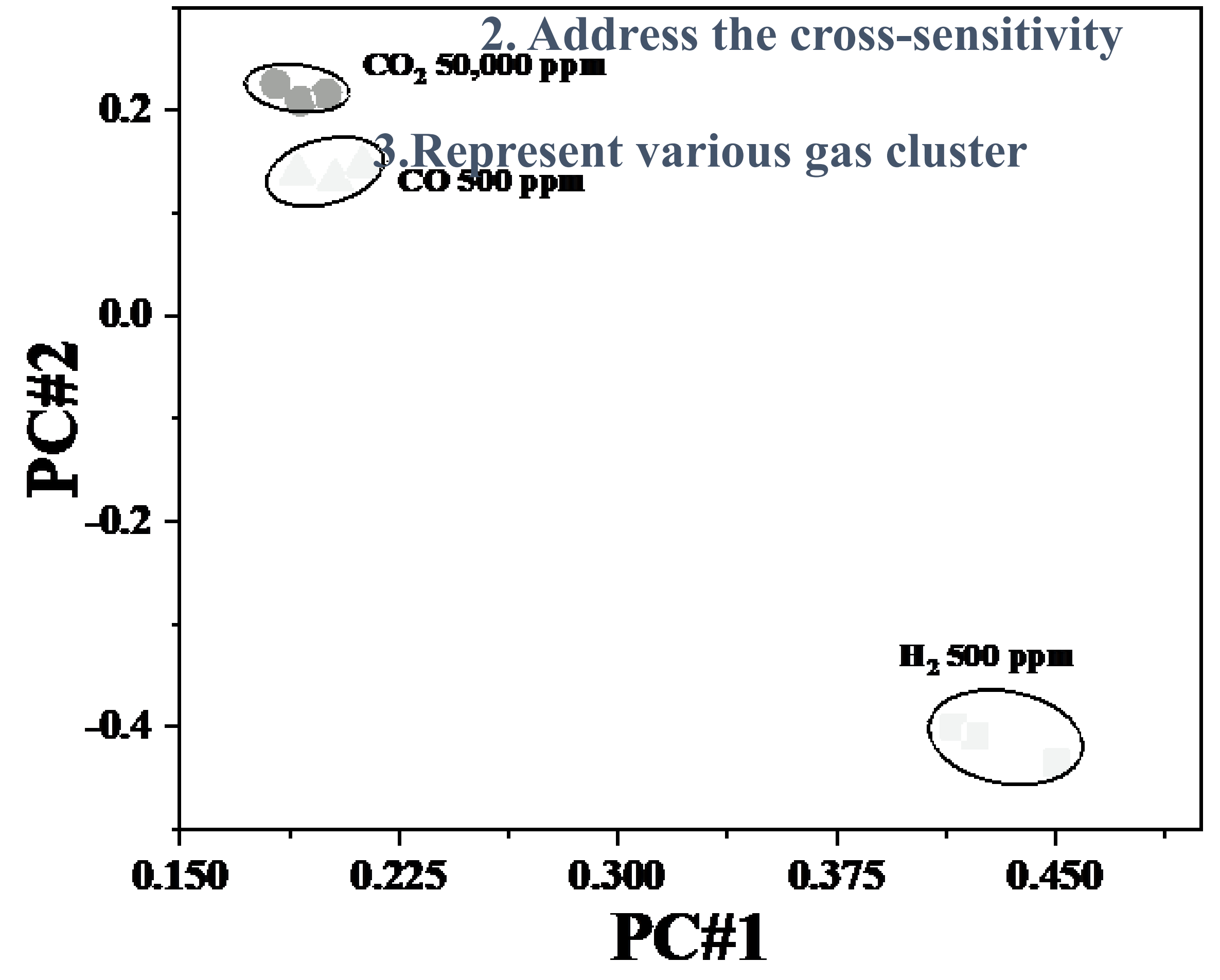


Principal component analyses (PCA)

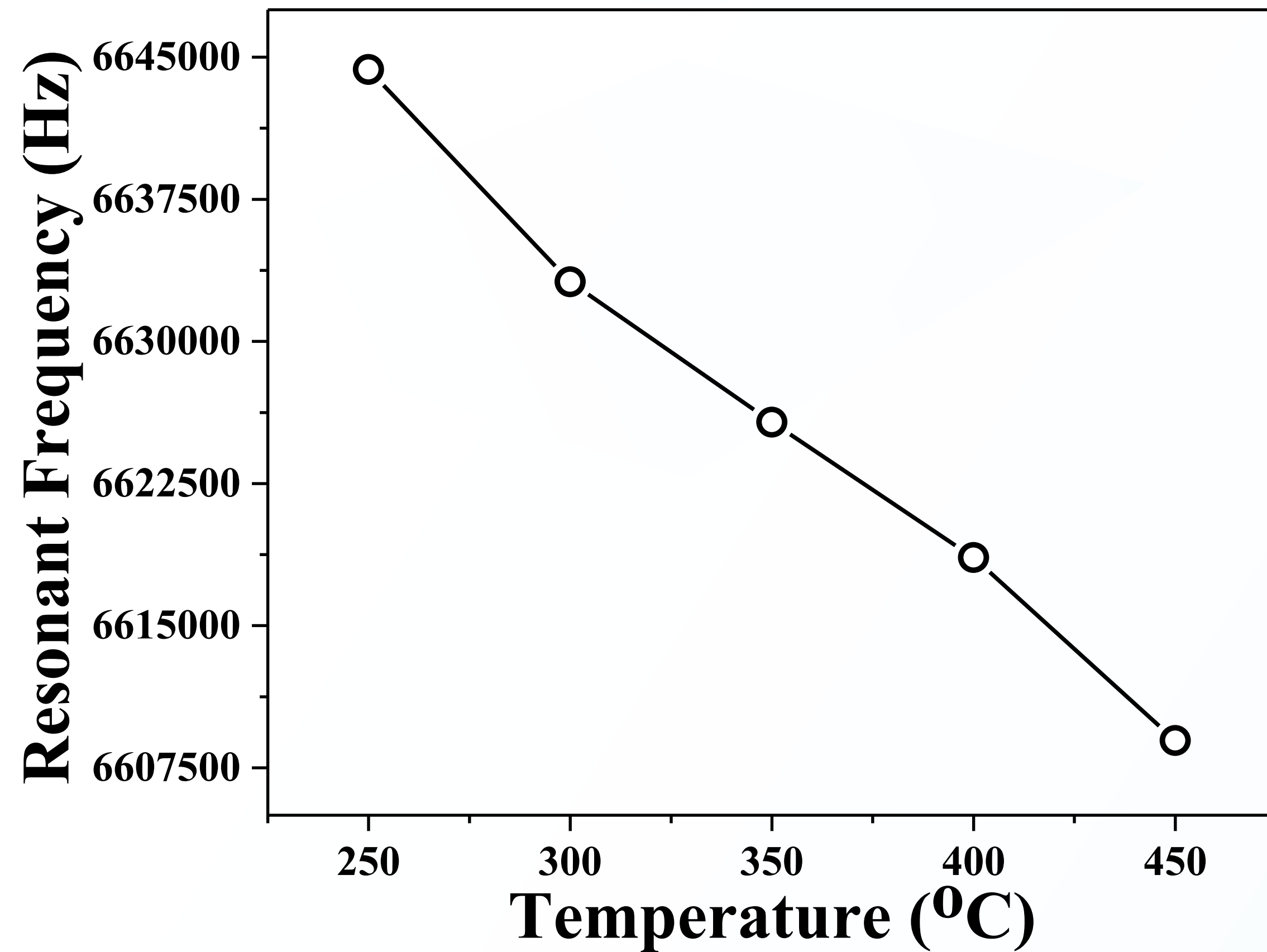
1. Unsupervised pattern recognition technique

2. Address the cross-sensitivity

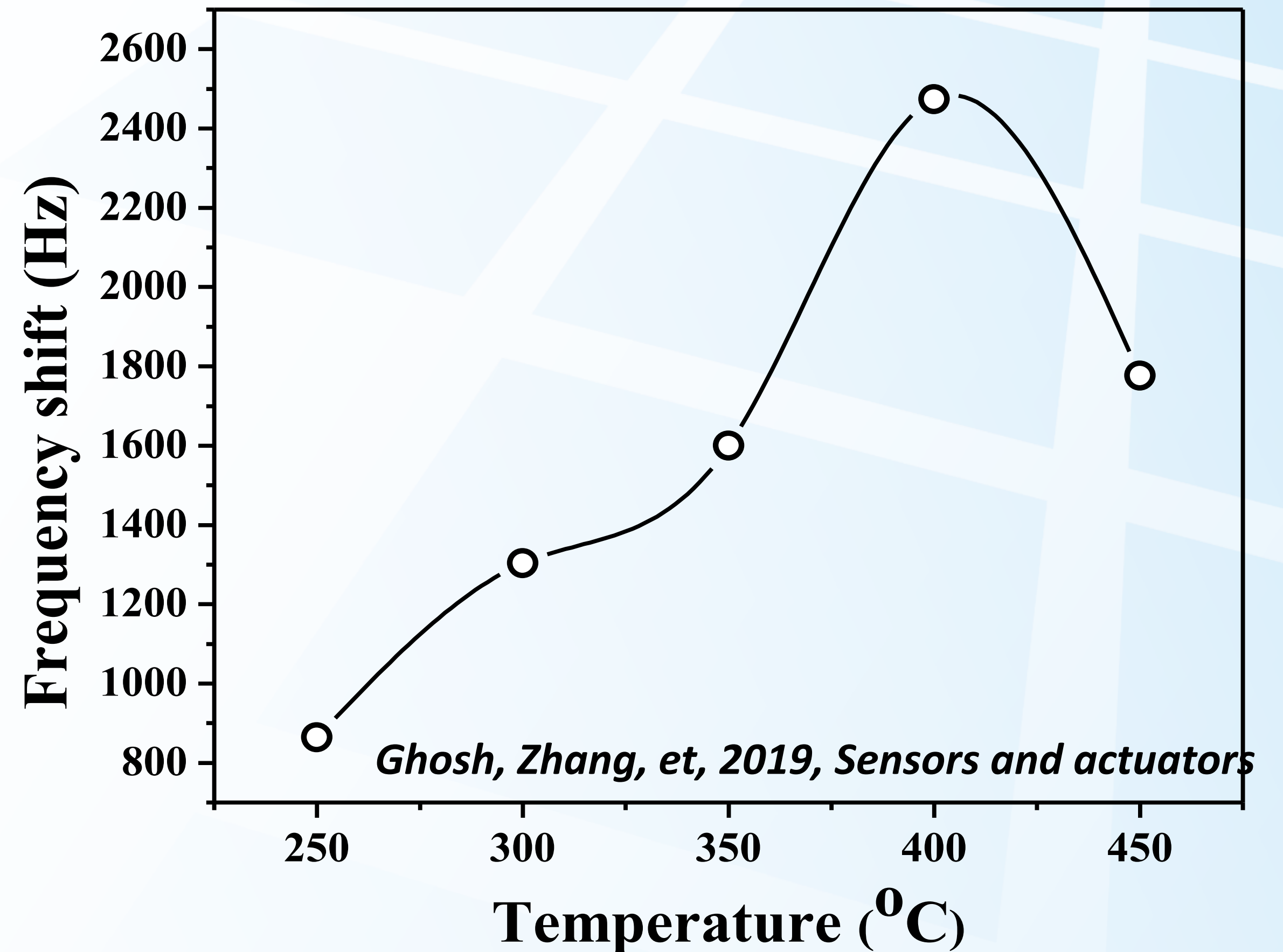
3. Represent various gas cluster

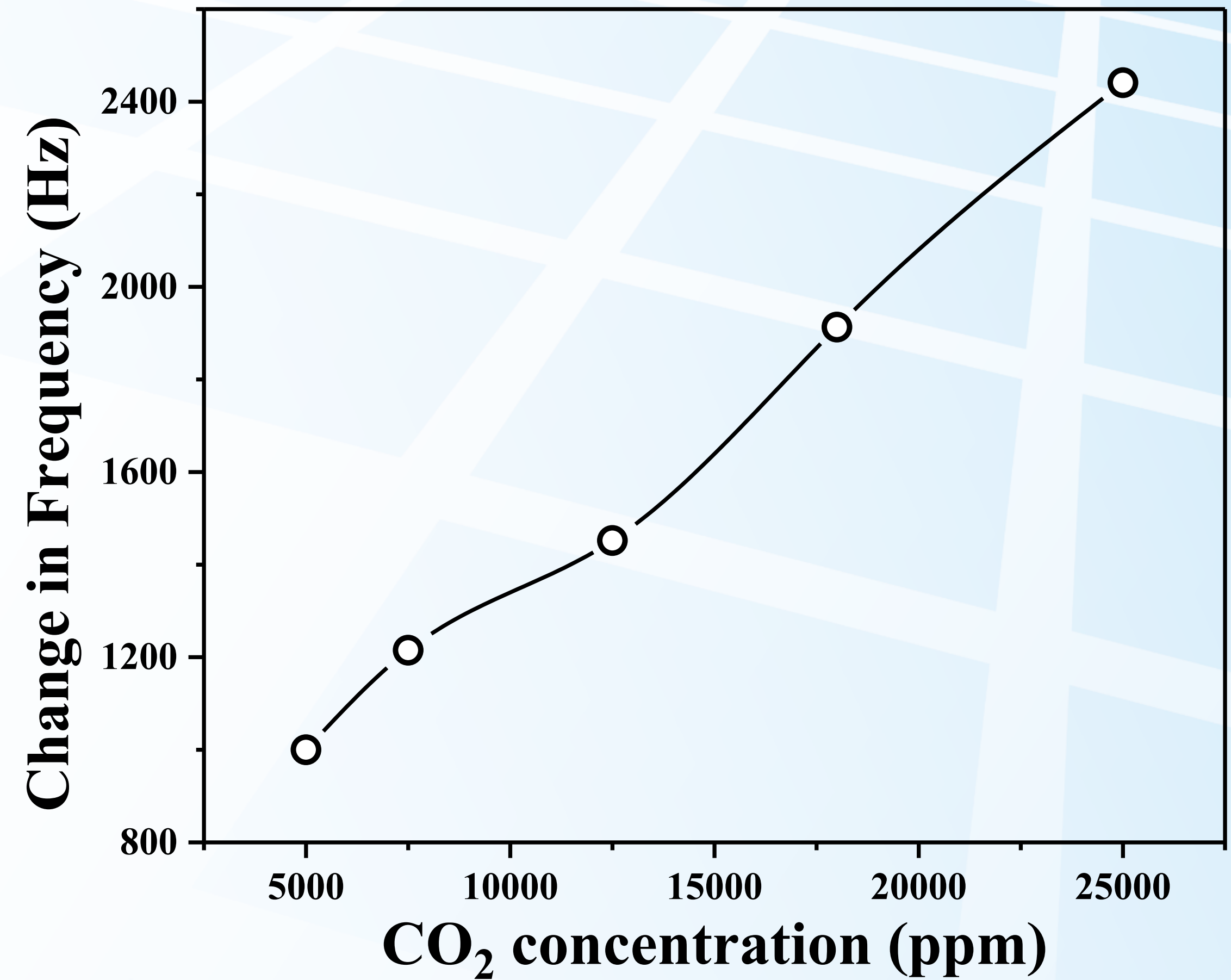
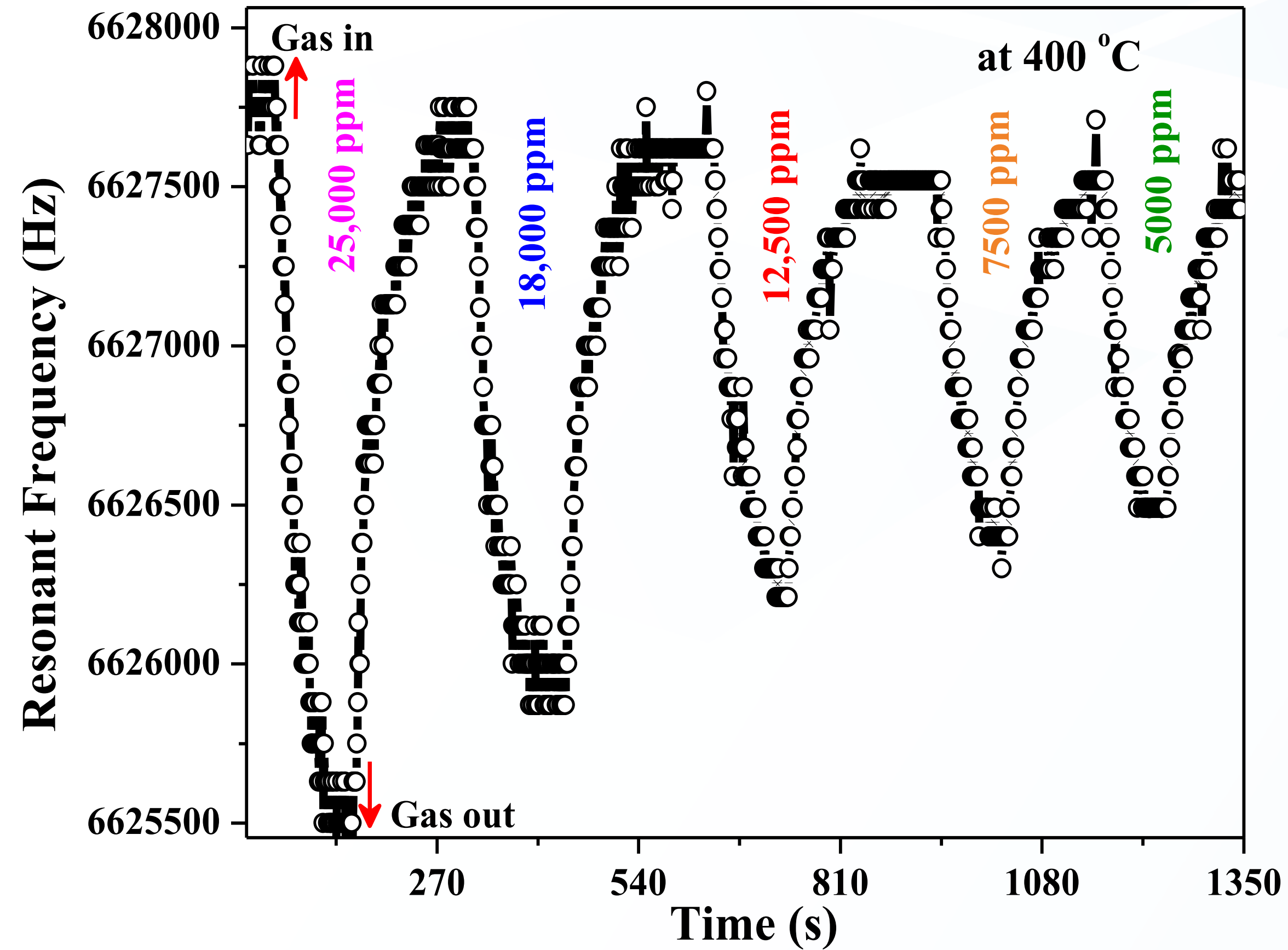


Temperature effect on resonant frequency



Temperature dependent CO₂ sensing





Comparison of High Temperature CO₂ sensors

Materials	Synthesis Method	Operating temperature	Optimum temperature	gases	Response(%)	Cross-sensitivity	Reference
Calcium/aluminum co-doped zinc oxide (ZnO:(Ca,Al)) nanoparticles (NPs),	Wet chemical	200 to 450 °C	200 °C (ZnO:Ca3Al1 under UV) 300 °C (ZnO:Al1% Ca 3%) 450 °C (ZnO:Ca5)	CO ₂ (0.25% to 5%)	~4.5(R _O /R: ZnO:Al1% Ca 3%) ~4 (UV)	NA	Dahiri et al. SNB, 2017, 239, 36.
pure ZnO and La-loaded ZnO (powder)	hydrothermal method	250 to 400°C	400 °C .	CO ₂ (5000 ppm)	65% (ΔR/R _a) (50 at% La-loaded ZnO)	Not performed	Jeong et al. SNB, 2016, 229, 288
SnO ₂ thick film by coating lanthanum oxide	Wet chemical	400 to 1200°C	1000 °C	CO ₂ (5000 ppm)	1.375 (R _a /R _g)	Not performed	Kim et al. SNB, 2000, 62, 61
1.Ca doped ZnO thin film (chemo-resistive). 2.Ca_ZnO coated LGS based SAW sensor.	Wet chemical	200 to 450°C	350 °C for Chemo-resistive 400°C for SAW	CO ₂ (5000 to 75,000ppm)	52% (ΔR/R _a) for 50,000 ppm. (Chemo-resistive) Δf = 2400 Hz (SAW)	Cross-sensitive	Present work

Comparison with the commercial CO₂ sensors

Method	Concentration range	Response time	Temperature range	Reference
NDIR type	0 to 40,000 ppm (accuracy 400-10,000 ppm)	20 s	40-70 °C	Sensirion
NDIR type	300 -5000 ppm	2 min	0-50°C	Figaro
NDIR type	0 to 100,000 ppm	2 min	25°C	Vernier
MOX and SAW (Ca_ZnO coated LGS)	0 to 75,000 ppm	~115 sec (MOX) ~30 sec (SAW)	200 to 450 °C	Present work

Conclusion

- ❑ Ca_ZnO thin film successfully deposited on quartz and LGS substrate.
- ❑ Higher response is achieved for a wide concentration of CO₂ gas.
- ❑ Cross-sensitivity is addressed using PCA analyses.
- ❑ Optimum CO₂ response is obtained at 350 and 400°C for metal oxide and SAW sensors respectively.
- ❑ CO₂ sensing enhanced due to catalytic effect of calcium.

Future works

- ❑ CO₂ sensing and its cross-sensitivity in various mixed gas environment at high operating temperature should be investigated further.

ZnO nanorods enhanced Langasite MEMS micro-cantilever gas sensor

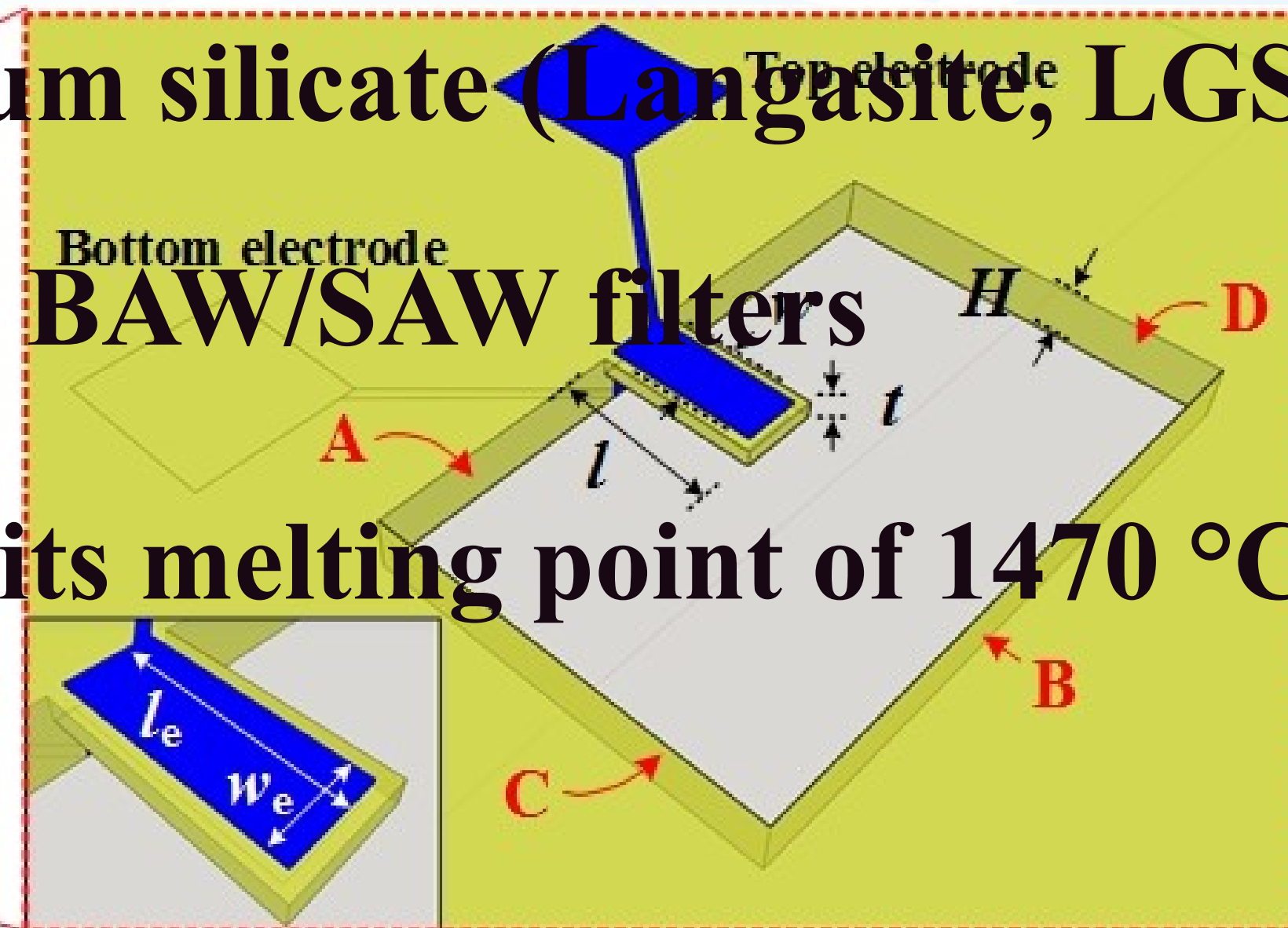
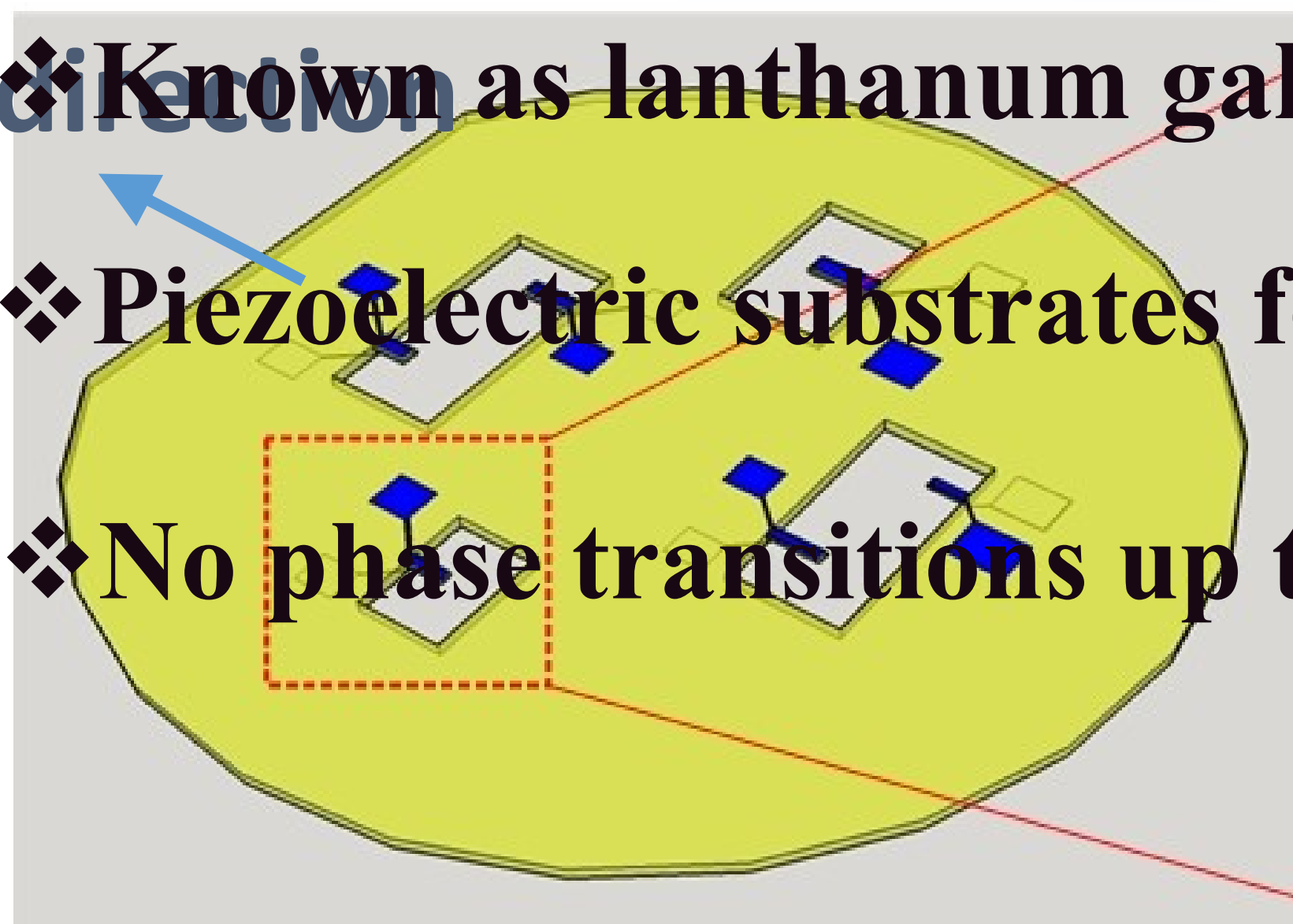
Thickness shear mode vibration of LGS MEMS

Y-cut thickness shear mode Langasite (LGS)

❖ Known as lanthanum gallium silicate (Langasite, LGS)

❖ Piezoelectric substrates for BAW/SAW filters

❖ No phase transitions up to its melting point of 1470 °C



t =thickness of cantilever,
 w =width of cantilever,
 l =length of cantilever,
 h =thickness of the substrate,
 w_e =width of electrode, and
 l_e =length of electrode

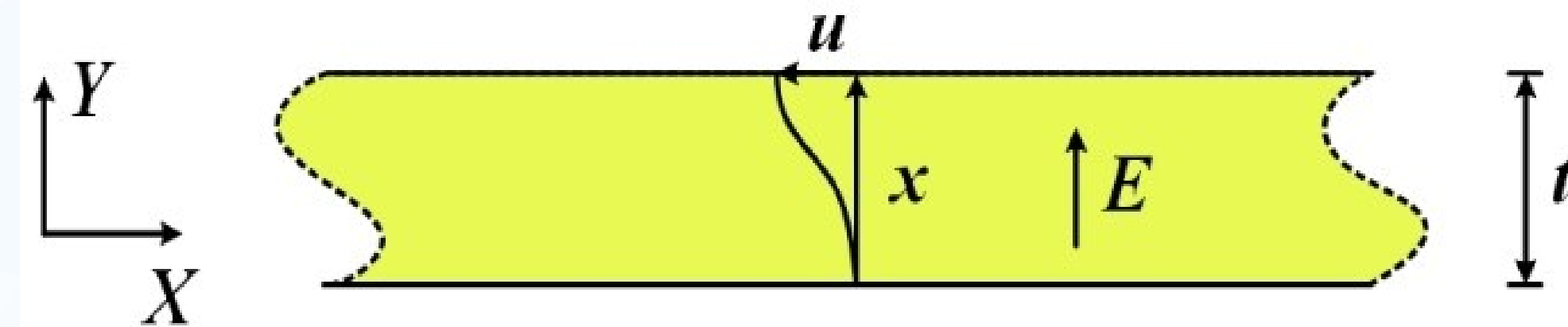
3D piezoelectric equations

$$\begin{pmatrix} c & e^T \\ e & \epsilon \end{pmatrix} \cdot \begin{pmatrix} S \\ E \end{pmatrix} = \begin{pmatrix} T \\ D \end{pmatrix}$$

$$\begin{pmatrix} s & d^T \\ d & \epsilon \end{pmatrix} \cdot \begin{pmatrix} T \\ E \end{pmatrix} = \begin{pmatrix} S \\ D \end{pmatrix}$$

$$s = c^{-1}$$

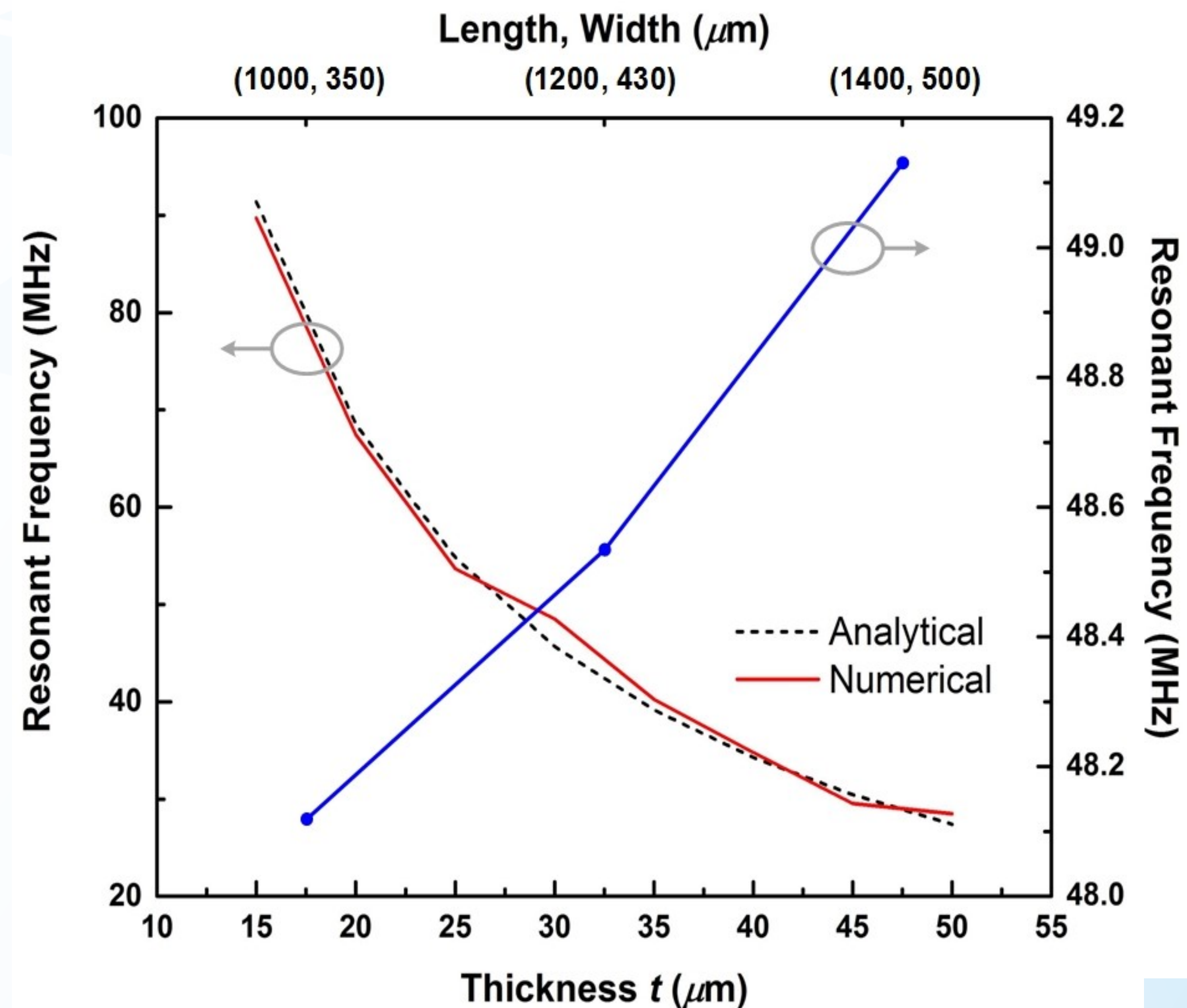
$$d = e \cdot s = e \cdot c^{-1}$$



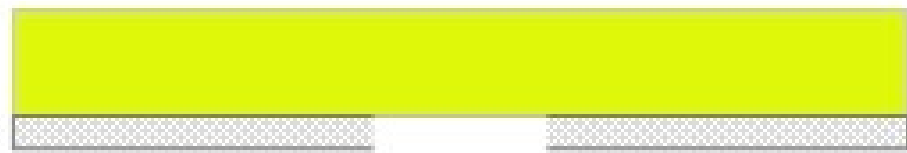
Thickness shear mode vibration of LGS MEMS

The resonant frequency of thickness shear mode resonance is **uniquely determined** by the **material properties** as well as the cantilever **thickness t** instead of its structured length and width.

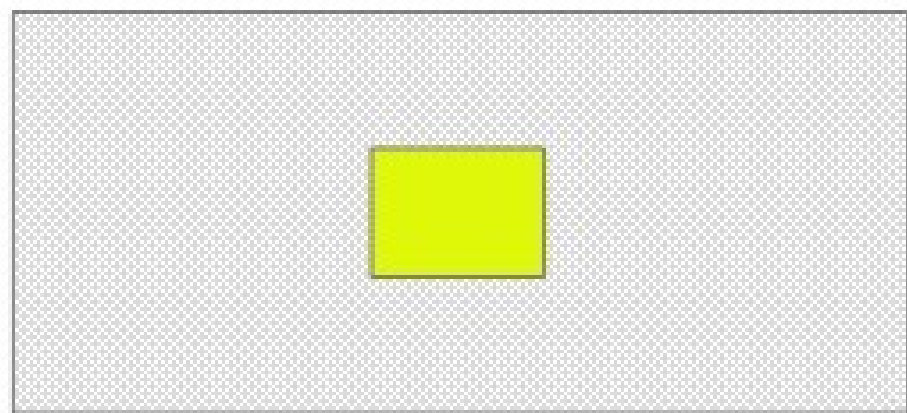
- ❑ Thickness of the resonator determines its resonant frequency
- ❑ Analytical results match the numerical results
- ❑ Length/width also affects the resonant frequency with a negligible effect.



1. Definition of SU-8 etch mask



(a) Side view



(b) Bottom view

2. Wet etch of LGS



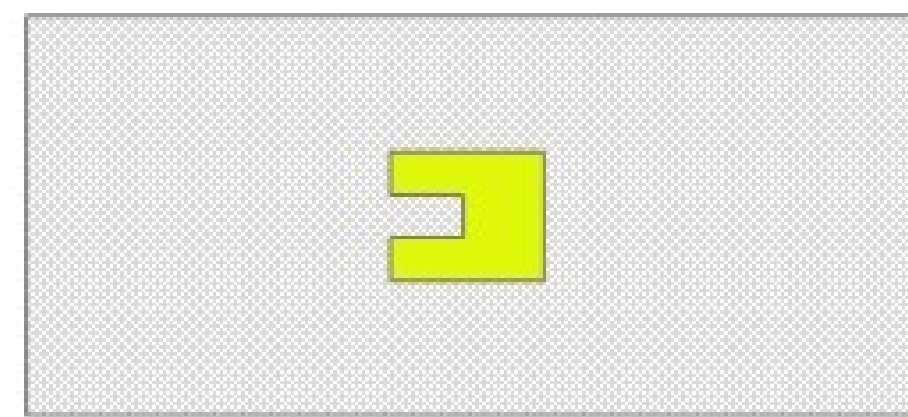
3. Top Pt deposition



4. Definition of SU-8 etch mask

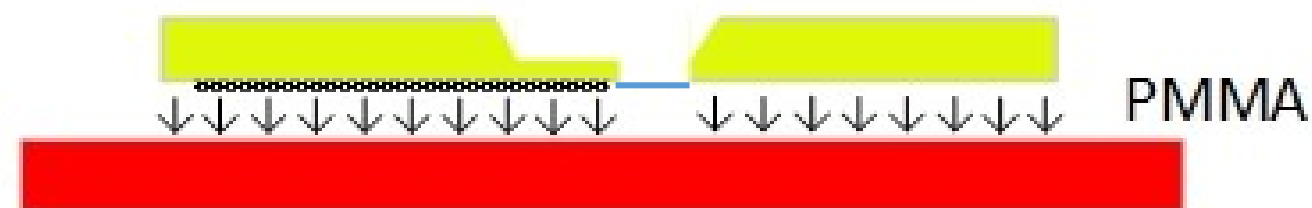


(a) Side view

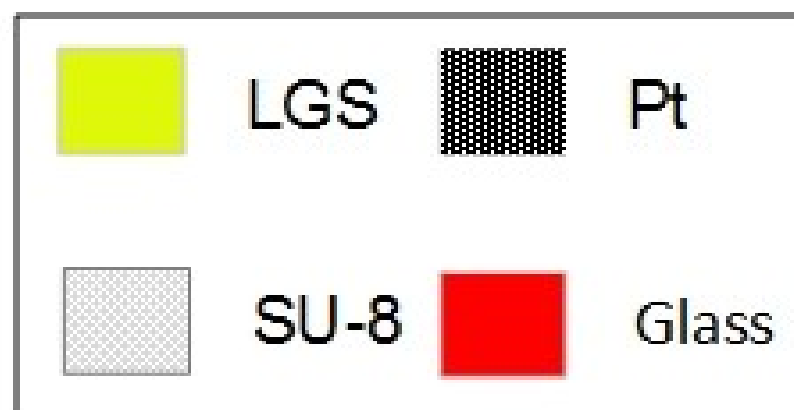
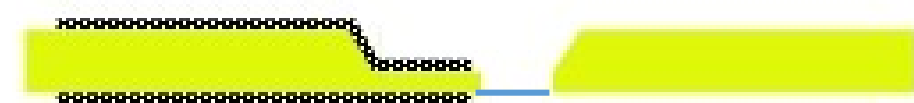


(b) Top view

5. Flip sample and bond with Si wafer



6. Bottom Pt deposition and detach sample from glass

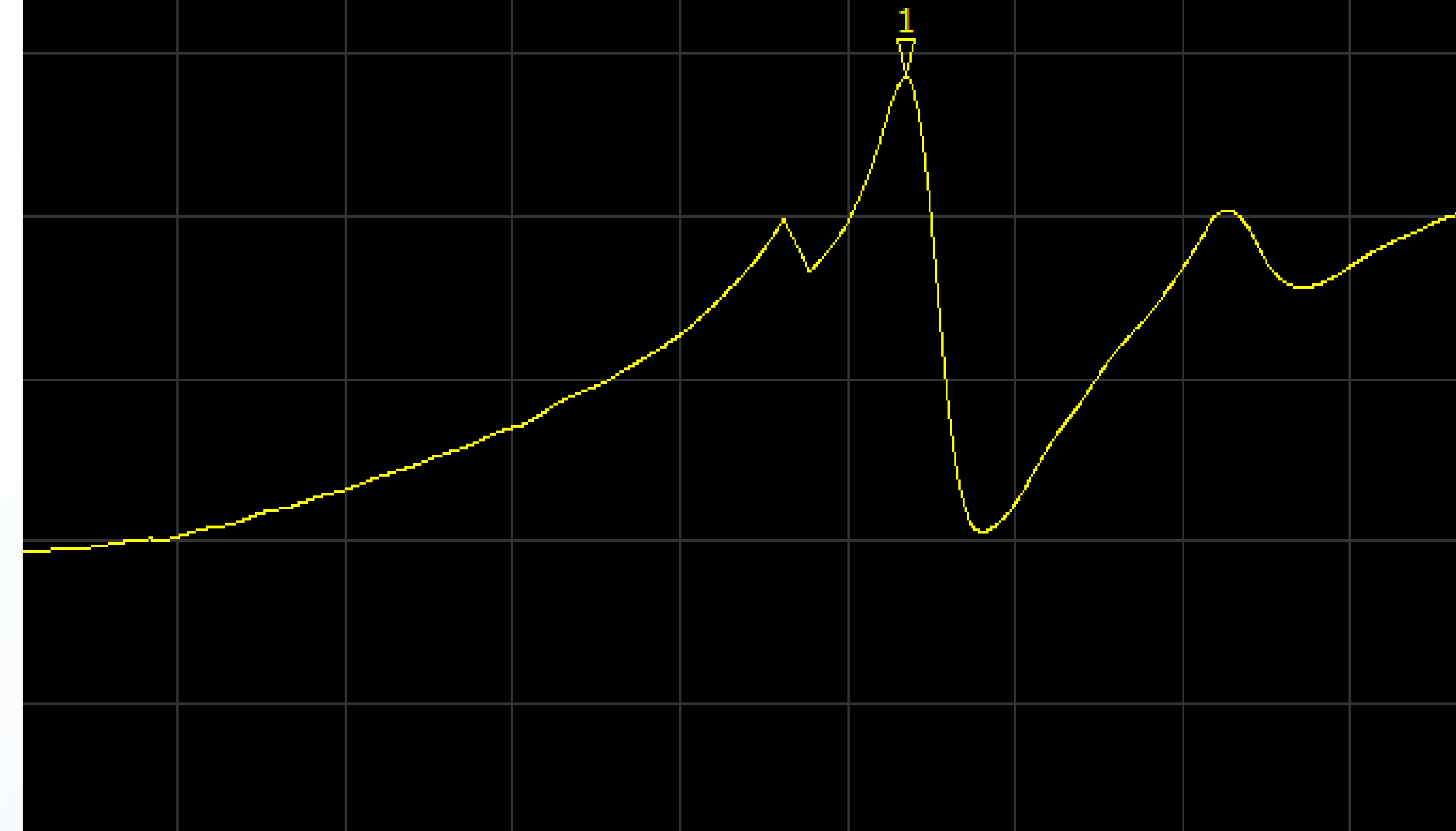


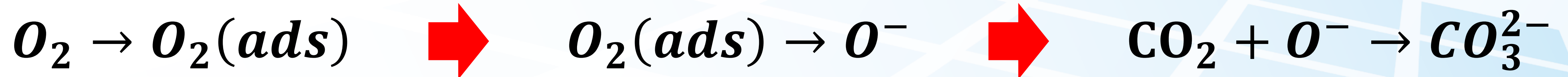
log Mag 50.00 mdB/ Ref -29.55 dB [smo]

>1 60.791500 MHz -29.457 dB

BW: 0.00000000 Hz
cent: 0.00000000 Hz
low: 0.00000000 Hz
high: 0.00000000 Hz
Q: 0.0000
loss: -29.457 dB

5 System





Sample exposed to gas species with certain concentration

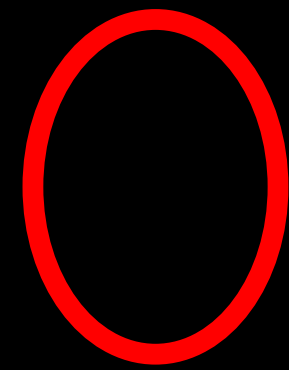
Chemical reaction with electron transfer take place at the solid-gas interface

Temperature change

Gas concentration change

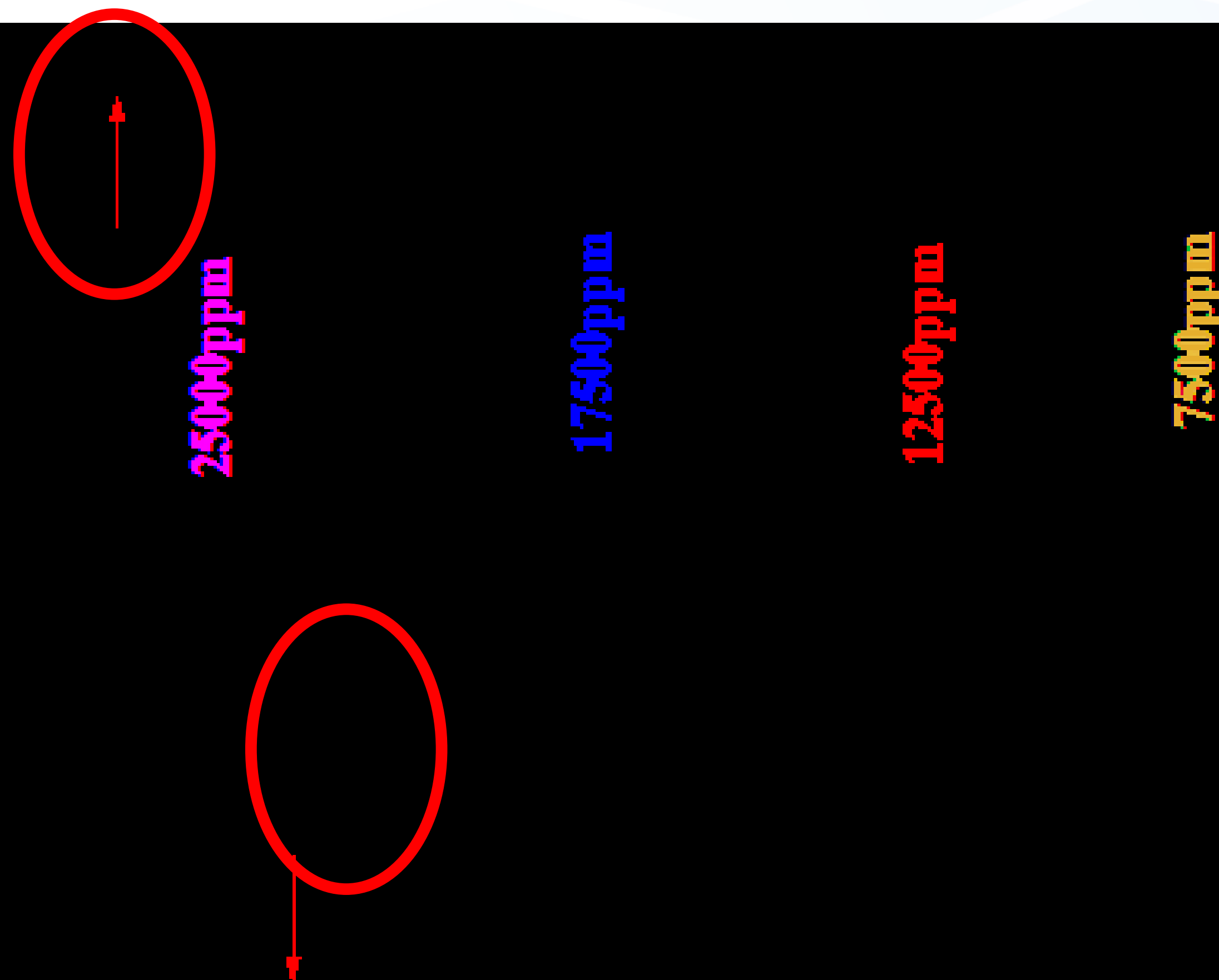
Gas molecules are chemisorbed on the resonator surface

Frequency drift induced by added mass from chemisorption



- ❑ Sensor is tested with 100% pure CO₂, by which the resonant frequency drift of the sensor is tracked.
- ❑ Optimum temperature is 400°C, where maximum sensor response is measured.

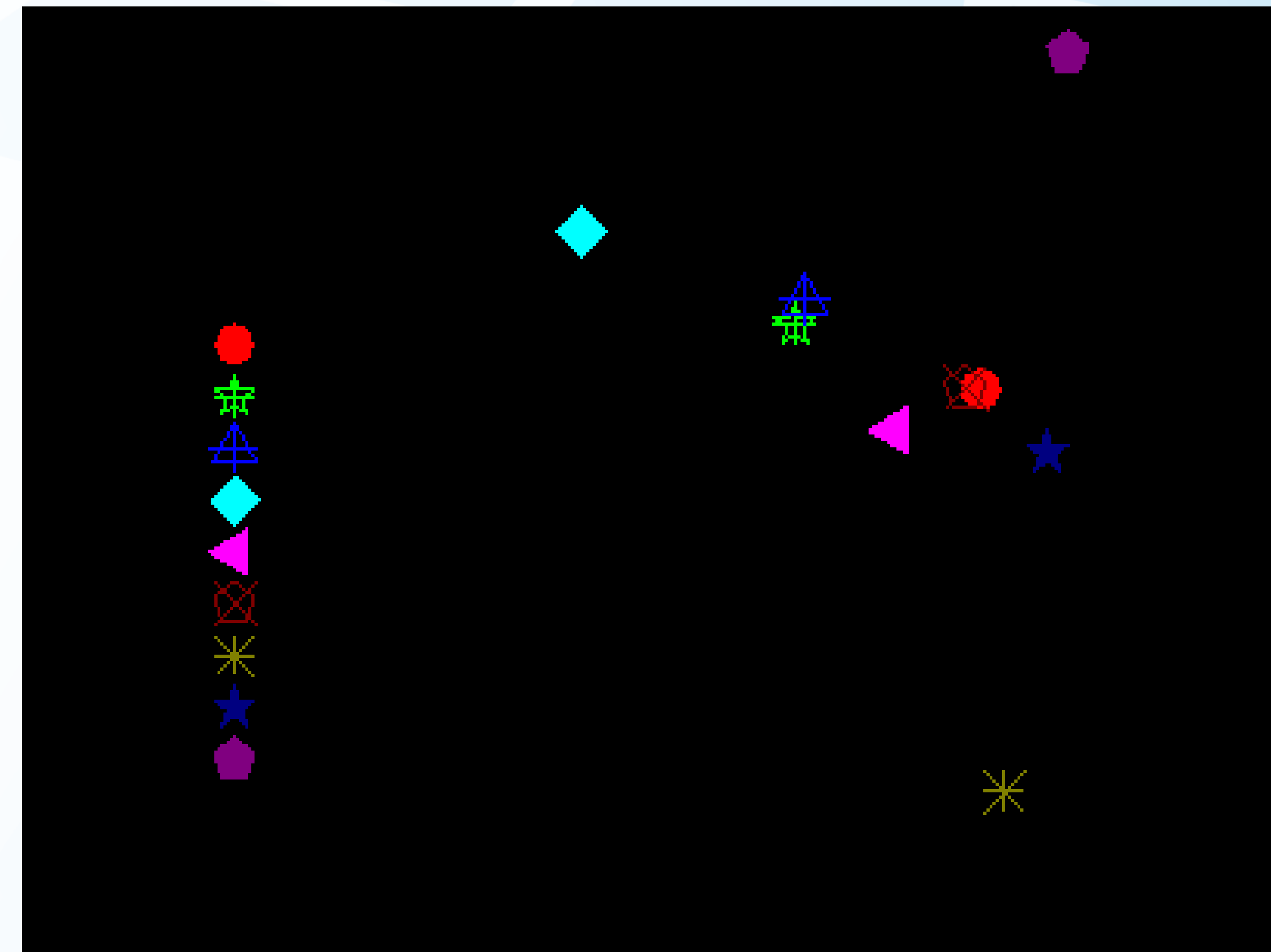
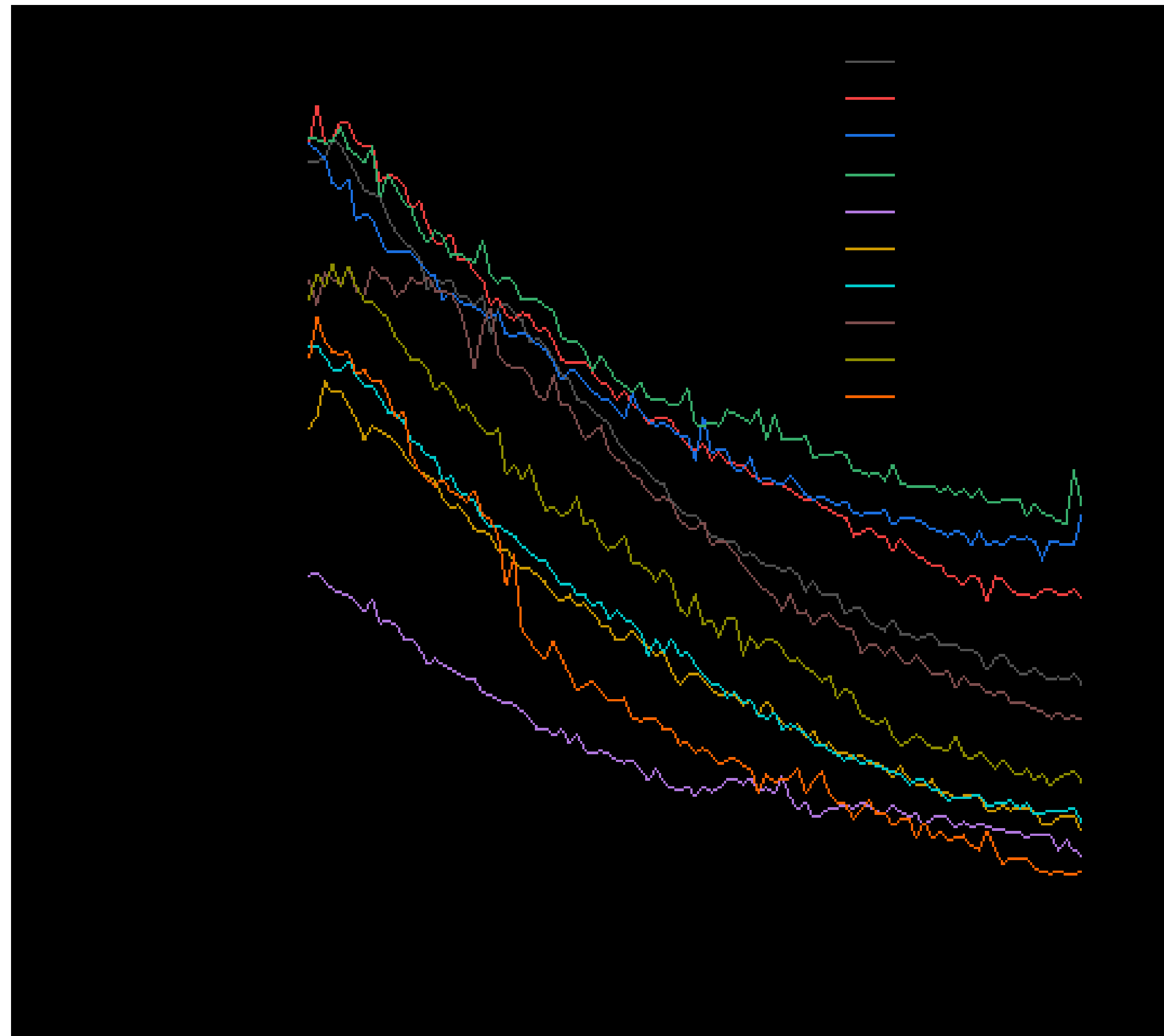
LGS MEMS with ZnO thin film for gas sensing



Resonators	Maximum Relative Sensitivity (df/f0/delta ppm)
LGS MEMS micro-cantilever with ZnO	0.02
Naked QCM	6.67e-6
QCM with calix [2] modified CNT films	1.25e-5
QCM with rough Ag electrode	8e-5
Unpolished QCM with PMMA film	1.2e-4
QCM with Multivalent Amino-Functionalized calix[4]arenes	2e-4
Multilayered ZnO FBAR gas sensor	1.18e-3

Cross-sensitivity is analyzed for real environment gas sensing application with the principle component analysis (PCA) technique.

ZnO thin film based LGS MEMS micro-cantilever gas sensor PCA results: PC2 vs. PC1 plot for N₂, air, and 100% CO₂ at 400°C.



Conclusion

- ❑ Piezoelectric-based BAW resonator (MEMS micro-cantilever) are responsive to mass loading from various test gas concentration/species. Their sensitivities are dependent on the nature of the material, vibration mode, and sensing thin film deposition.
- ❑ MEMS resonator can be successfully applied for potential gas sensing and performs an outstanding sensitivity by taking the advantage of their high resonant frequency as well as utilization of sensing thin films
- ❑ Metal oxides (ZnO) can improve the sensing performance by acting as catalyst for oxygen pre-adsorption at certain temperature as well as the chemisorption of test gas species.

Future works

- ❑ Performance enhanced MEMS technique will be adopted, which is expected to improve the Q-factor of MEMS micro-cantilever resonator.
- ❑ Real environment tests will be carried out with performance enhanced gas sensor for a comprehensive mixed gas measurement, which is expected to address the gas sensing problem in reality.
- ❑ Sensor pack or sensor fusion will be implemented to exploit a gas sensing terminal with advanced sensor signal processing algorithm for future commercial/industrial application.

Acknowledgments

Mr. Zhang Chen, Dr. Abihesh Ghosh, Dr. Suresh Kaluvan, Mr. Pham Toug



Questions

